

IN THE CLAIMS:

Please AMEND claims 1-3, 7, 9, 10, 20-24 and 26, as follows. For the Examiner's convenience, all claims currently pending in this application have been reproduced below:

1. (Currently Amended) A moving/guiding apparatus comprising:

a first movable body which moves in a first direction;

~~first and a second movable bodies guided to move in intersecting directions,~~  
~~arranged at vertically different positions, and restrained in a vertical direction~~ body which moves  
in a second direction intersecting with the first direction;

~~first and second actuators for driving said first and second movable bodies in the~~  
~~intersecting directions; and~~

a third movable body guided to be movable on a surface plate ~~in a moving~~  
~~direction of said first movable body and in a moving direction of said second movable body, and~~  
~~driven in two intersecting direction upon reception of forces from guide surfaces in a horizontal~~  
~~direction of~~ the first and second directions by receiving forces from said first and second  
movable bodies;

a first actuator for driving said first movable body in a first direction; and

a second actuator for driving said second movable body in the second direction,

wherein said first and second actuators are arranged outside of a container which  
accommodates said first, second and third movable bodies.

2. (Currently Amended) The apparatus according to claim 1, wherein an inside of  
~~the apparatus further comprises a vacuum container for accommodating said first,~~  
~~second, and third movable bodies, and~~  
~~said first and second actuators are set outside said vacuum container~~ is at a  
vacuum or a non-atmospheric pressure.

3. (Currently Amended) The apparatus according to claim 1, further comprising:  
first and second bearings for guiding one side of said first movable body and one  
side of said second movable body, respectively, and restraining said first and second movable  
bodies at least in vertical and horizontal directions, and  
third and fourth bearings for guiding the other side of said first movable body and  
the other side of said second movable body, respectively, and restraining said first and second  
movable bodies at least in the vertical direction.

4. (Original) The apparatus according to claim 3, wherein said first and second bearings  
are radial bearings.

5. (Original) The apparatus according to claim 1, further comprising a static pressure  
bearing for guiding said first, second and third movable bodies.

6. (Original) The apparatus according to claim 1, wherein said first and second actuators  
are ultrasonic linear motors.

7. (Currently Amended) The apparatus according to claim 2, further comprising  
a rigid body for transmitting driving forces from said first and second actuators to  
said first and second movable bodies, and  
a seal for sealing said rigid body and said vacuum container with a labyrinth seal  
structure.

8. (Original) The apparatus according to claim 1, wherein  
said first actuator includes a pair of linear motors for transmitting driving forces to  
two sides of said first movable body, and  
said second actuator includes a pair of linear motors for transmitting driving  
forces to two sides of said second movable body.

9. (Currently Amended) A moving/guiding method for a moving/guiding apparatus  
having ~~first and second movable bodies guided to move in intersecting directions, arranged at~~  
~~vertically different positions, and restrained in a vertical direction, a first movable body which~~  
~~moves in a first direction, a second movable body which moves in a second direction,~~  
~~intersecting with the first direction, and a third movable body guided to be movable on a surface~~  
~~plate in a moving direction of the first movable body and in a moving direction of the second~~  
~~movable body, and driven in the first and second directions by receiving forces from the first and~~  
~~second movable bodies, said method~~ comprising the steps of:

driving the first and second movable bodies by respective actuators in directions  
the first and second movable bodies are ~~guided~~, guided; and

driving the third movable body in two intersecting directions by forces from the guide surfaces in a horizontal direction of the first and second movable bodies.

10. (Currently Amended) The method according to claim 9, wherein an inside of  
~~the first, second, and third movable bodies are accommodated in a vacuum~~  
~~container, and the actuators are set outside the vacuum container~~ is maintained at a vacuum or a  
non-atmospheric pressure.

11. (Original) The method according to claim 9, wherein  
one side of the first movable body and one side of the second movable body are  
guided by a bearing restraining movement at least in vertical and horizontal directions, and  
the other side of the first movable body and the other side of the second movable  
body are guided by a bearing restraining movement at least in the vertical direction.

12. (Original) The method according to claim 9, wherein the first, second, and third  
movable bodies are guided by a static pressure bearing.

13. (Original) The method according to claim 9, wherein the first, second, and third  
movable bodies are guided by a static pressure bearing.

14. (Original) The method according to claim 9, wherein the actuators use ultrasonic  
linear motors.

15. (Original) The method according to claim 10, wherein  
forces from the actuators to the first and second movable bodies are transmitted  
through a rigid body, and  
the rigid body and the vacuum container are sealed with a labyrinth seal structure.
16. (Original) The method according to claim 9, wherein driving forces are transmitted to  
two sides of the first movable body by a pair of linear motors, and driving forces are transmitted  
to two sides of the second movable body by another pair of linear motors.
17. (Original) A device manufactured by using the moving/guiding apparatus according  
to claim 1.
18. (Original) A device manufactured by using the moving/guiding method according to  
claim 9.
19. (Original) An exposure apparatus using the moving/guiding apparatus according to  
claim 1.
20. (Currently Amended) A semiconductor device manufacturing method comprising the  
steps of:

setting a group of manufacturing apparatuses for performing respective types of processes, including the exposure apparatus according to claim 19, at a semiconductor manufacturing factory; and

manufacturing a semiconductor device in accordance with a plurality of processes by using the group of manufacturing apparatuses.

21. (Currently Amended) The method according to claim 20, further comprising the steps of:

connecting the group of manufacturing apparatuses to each other through a local area network, and

data-communicating information on at least one of the group of manufacturing apparatuses between the local area network and an external network outside the semiconductor manufacturing factory.

22. (Currently Amended) The method according to claim 21, wherein maintenance information on the manufacturing apparatuses is obtained through data communication by accessing a database provided by a ~~vender~~ vendor or user of the exposure apparatus through the external network, or production management is performed by data communication with another semiconductor manufacturing factory different from the semiconductor manufacturing factory through the external network.

23. (Currently Amended) A semiconductor manufacturing factory comprising:  
a group of manufacturing apparatuses for performing respective types of processes, including the exposure apparatus according to claim 19, and  
a local area network for connecting the group of manufacturing apparatuses, and a gateway for enabling access to an external network outside the factory from the local area network,  
wherein data communication of information on at least one of the group of manufacturing apparatuses is enabled.

24. (Currently Amended) A maintenance method for the exposure apparatus according to claim 19, which is set on a semiconductor manufacturing factory, said method comprising the steps of:

providing, by a ~~vender~~ vendor or user of the exposure apparatus, a maintenance database connected to an external network outside the semiconductor manufacturing factory;

allowing access to the maintenance database from inside the semiconductor manufacturing factory through the external network; and

transmitting maintenance information accumulated in the maintenance database to the semiconductor manufacturing factory through the external network.

25. (Original) The exposure apparatus according to claim 19, wherein  
the exposure apparatus further comprises a display, a network interface, and a computer for performing network software, and

data communication of maintenance information on the exposure apparatus through a computer network is enabled.

26. (Currently Amended) The exposure apparatus according to claim 25, wherein the network software provides a user interface for accessing a maintenance database, connected to an external network outside a factory where the exposure apparatus is set and provided by a ~~vender~~ vendor or user of the exposure apparatus, on the display, so information can be obtained from the database through the external network.